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FIG. 1A

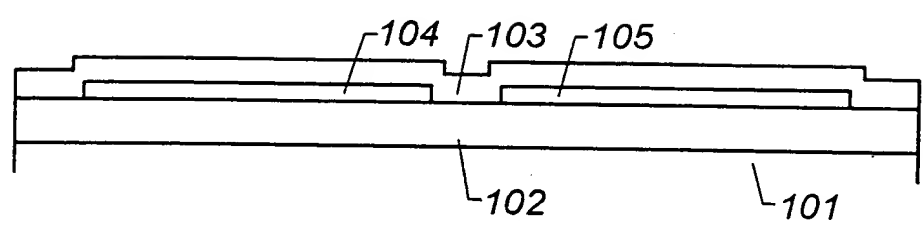


FIG. 1B

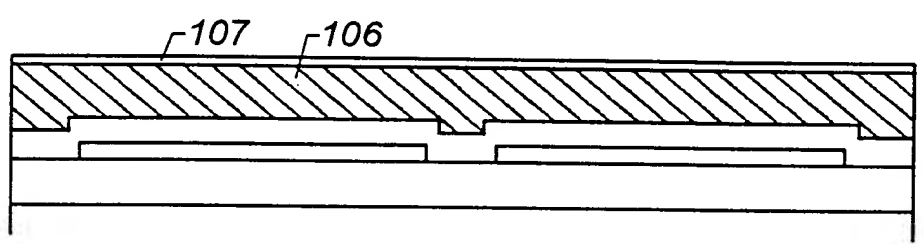


FIG. 1C

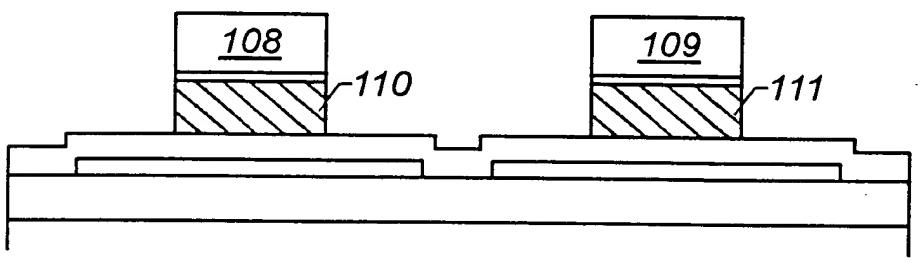


FIG. 1D

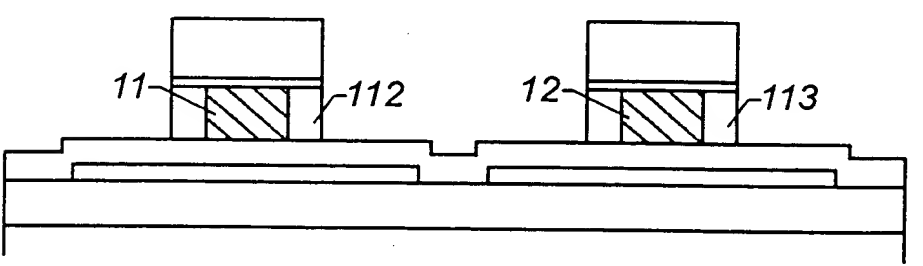


FIG. 1E

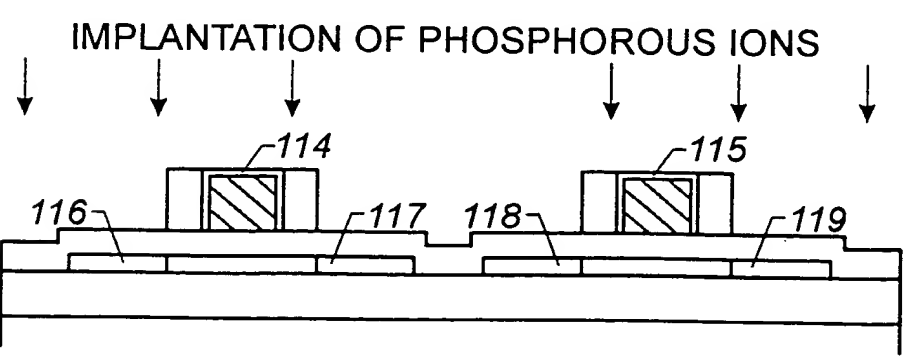


FIG. 2A

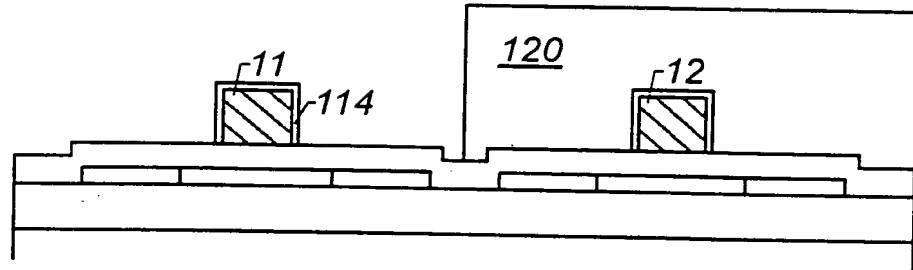


FIG. 2B

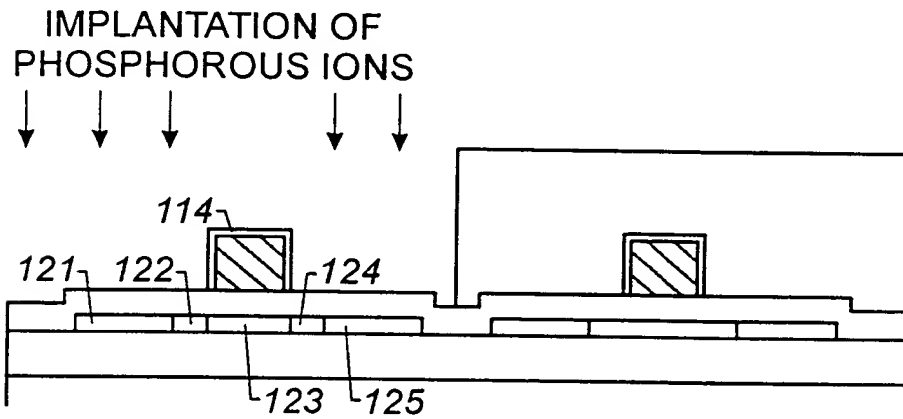


FIG. 2C

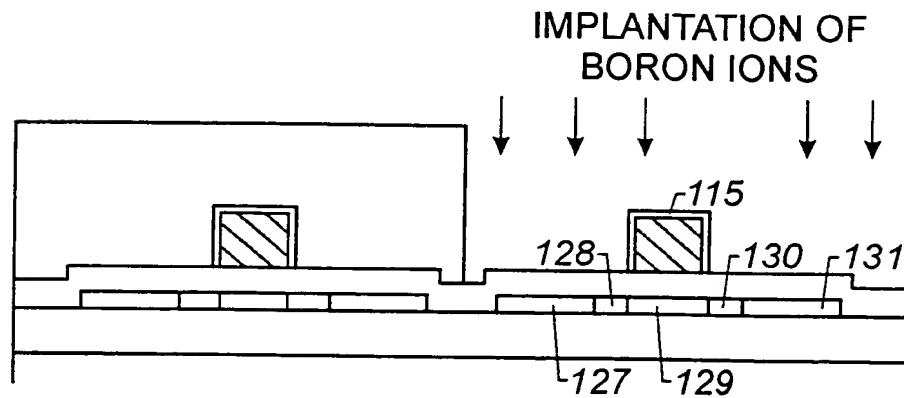


FIG. 2D

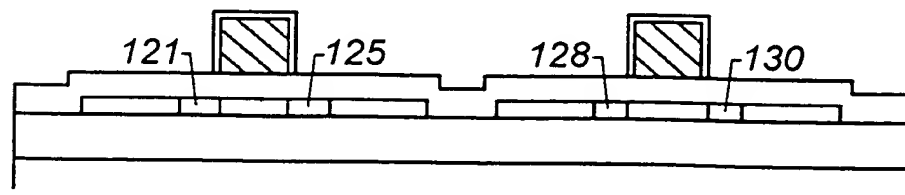


FIG. 3A

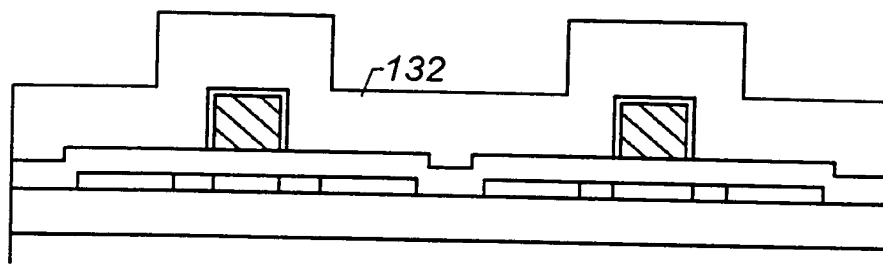


FIG. 3B

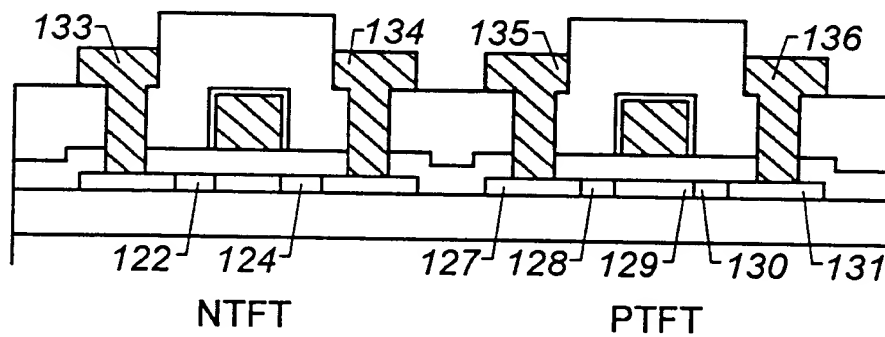


FIG. 4A  
(PRIOR  
ART)

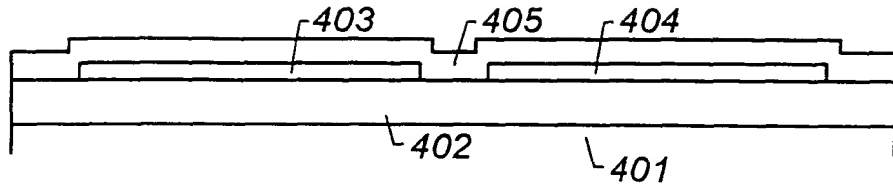


FIG. 4B  
(PRIOR  
ART)

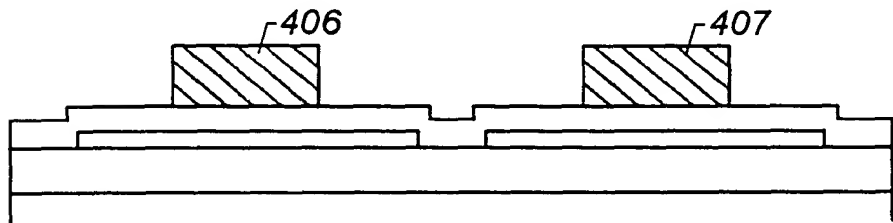


FIG. 4C  
(PRIOR  
ART)

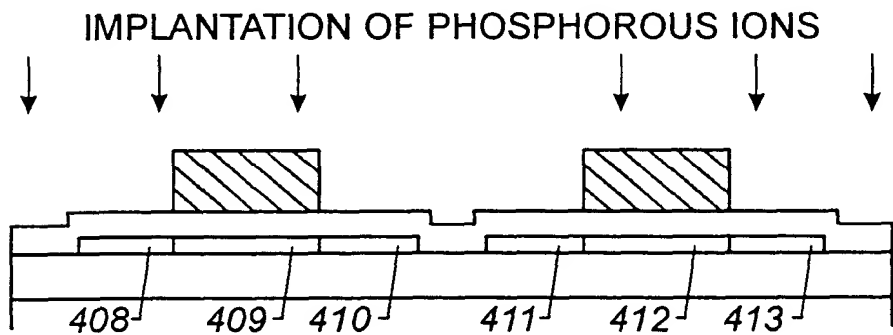
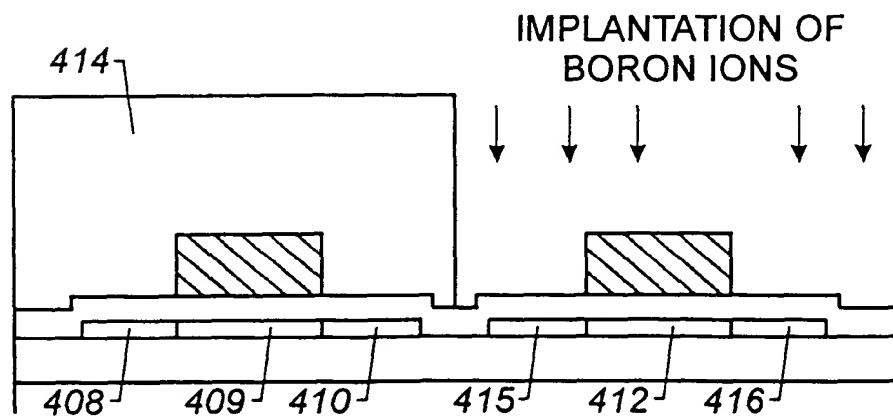
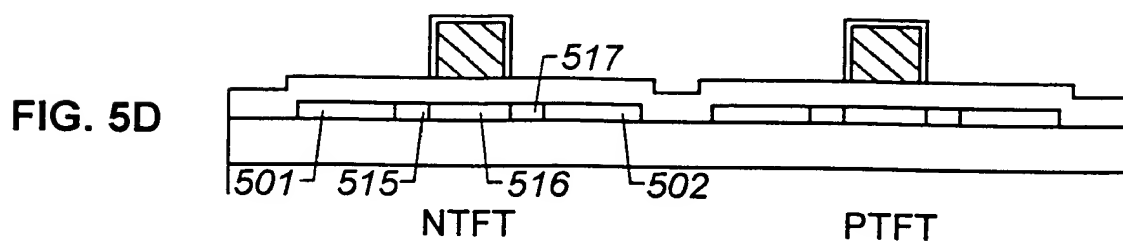
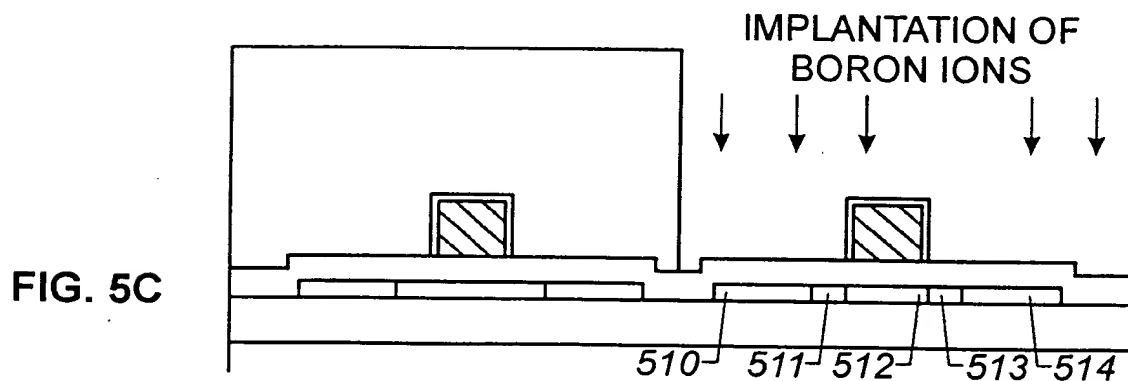
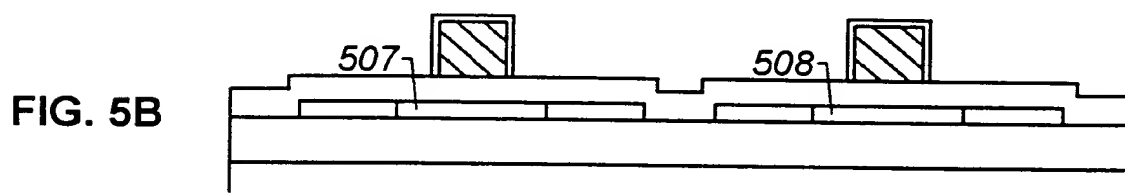
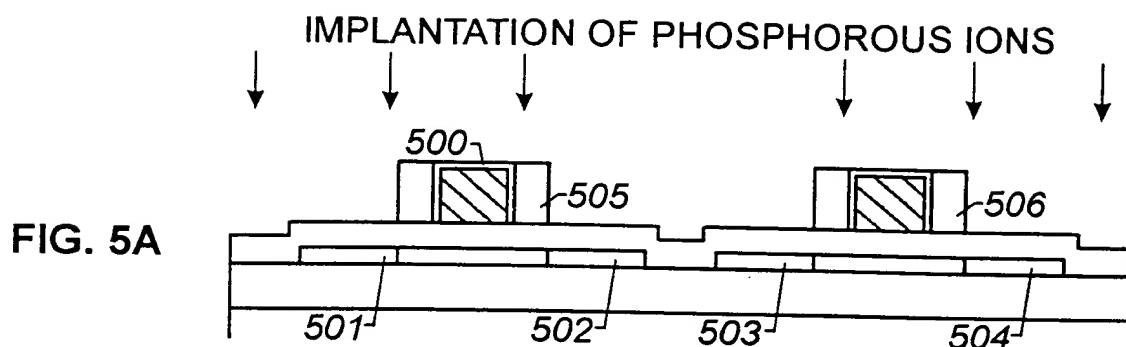


FIG. 4D  
(PRIOR  
ART)





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FIG. 6A

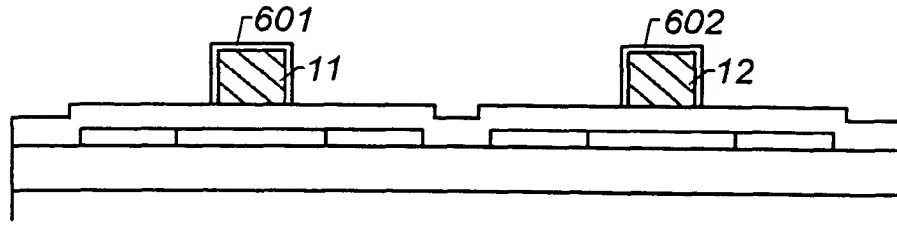


FIG. 6B

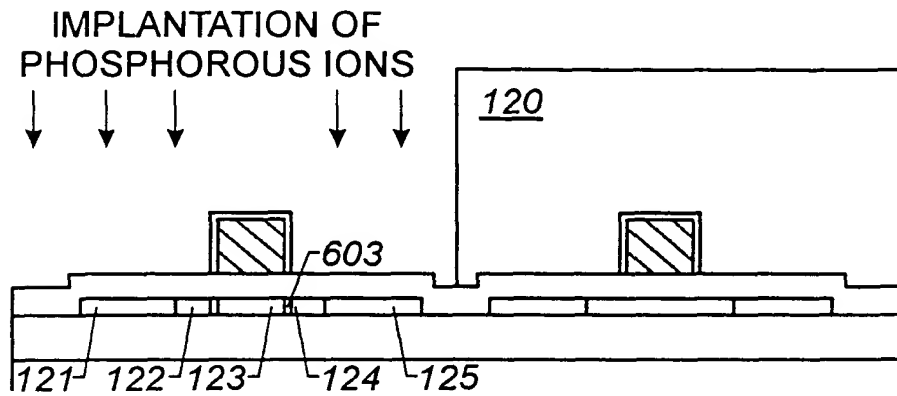


FIG. 6C

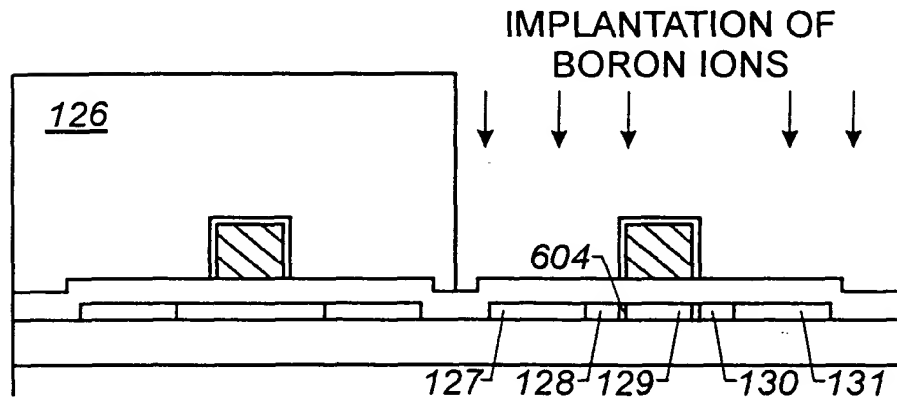
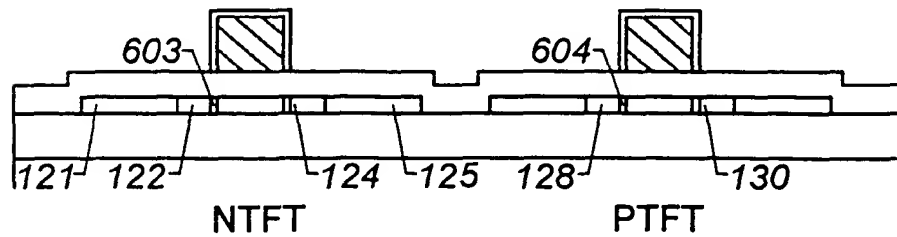


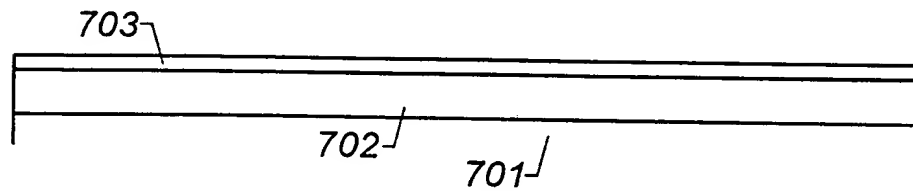
FIG. 6D



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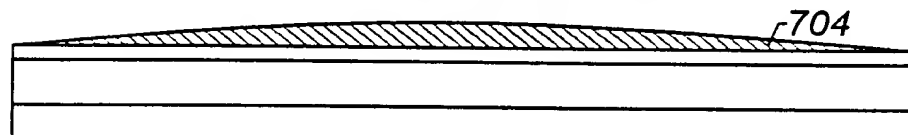
FORMATION OF AMORPHOUS SILICON FILM

FIG. 7A



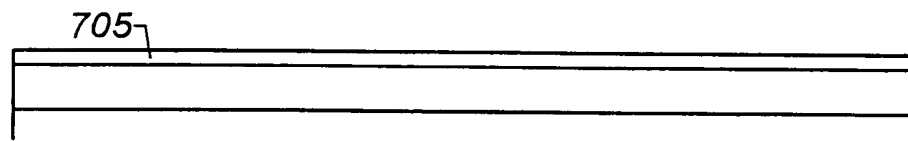
FORMATION OF WATER FILM  
CONTAINING NICKEL SALT

FIG. 7B



HEATING PROCESS FOR CRYSTALIZATION

FIG. 7C



HEATING PROCESS IN ATMOSPHERE  
CONTAINING HALOGEN ELEMENT

FIG. 7D

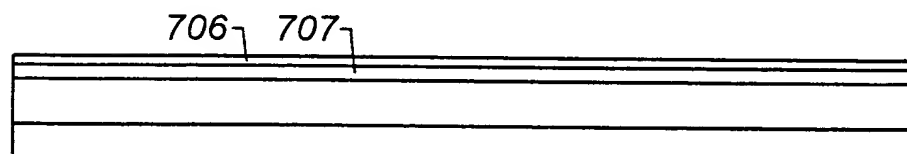


FIG. 7E

